

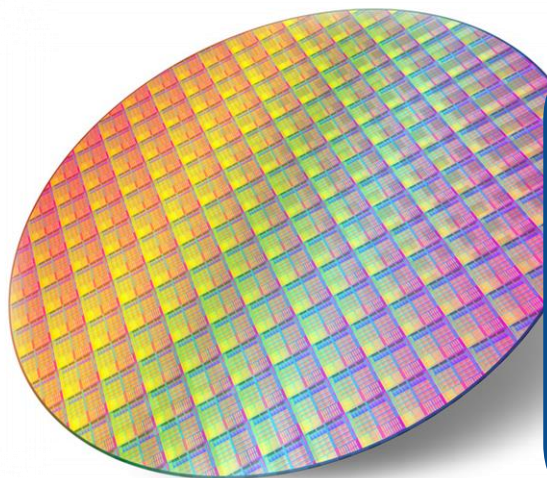
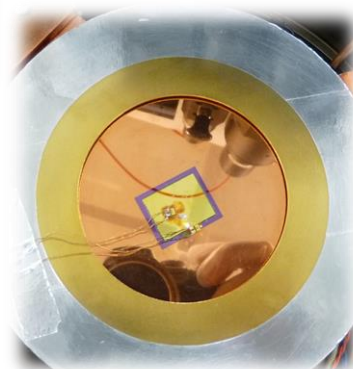
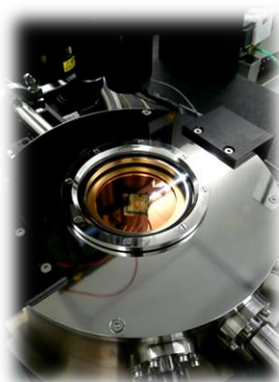


- Contact & Non-Contact Surface Instrument
- Stroke: 300 X 300 X 300 mm & Rotary Axis
- Measuring Range: from 100µm to 27mm
- Vertical Resolution: down to 1nm
- AltiMap Analysis software
- Imaging Camera

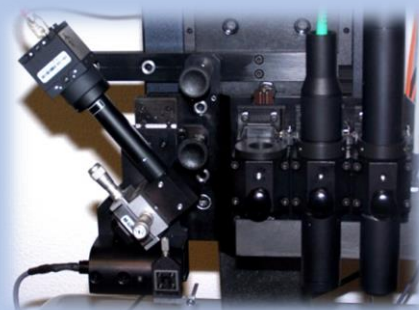


With its big size and simplified software interface, the AltiSurf 530 will meet your measurements needs from the laboratory to the workshop.

The wide range of optical sensors makes possible roughness, flatness and dimensional measurements.



- Full PheNIX®inside
- ISO 25178 inside
- CHROMATIC
- EMBEDDABLE
- OEM-READY
- 7D DATA
- CLIENT-SERVER / IP
- POINT PROFILER
- LAB to LINE
- MODAL®inside



Axes and travel

Stroke X, Y, Z (mm) : 300 x 300 x 300
DC or Piezo motorized axes
Flatness 2 nm/mm local
Max. speed: up to 100 mm/s
Options: 22 nm encoders, rotary axis

Sensors

Several kinds of sensors available :
Non-contact confocal chromatic POINT or Line
Triangulated laser
Tactile Inductive Stylus, Micro-Force Stylus
CCD Camera

HMI

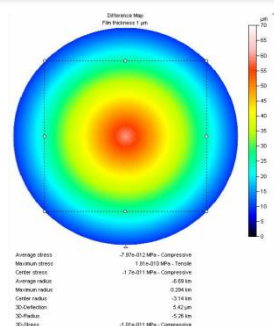
Automated production control mode
SPC link
Shop floor control (green/red light status)
Easy user protocol definition by self-learning

Qualifications

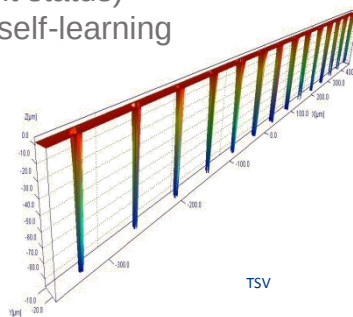
CE , UL, CSA compliance
Safety machine

AltiSurf® 530 allows you to study the relationships between surface statements and performances -or quality- expectations (Functionality, aspect, ageing, wearing, porosity, adherence, aspect...)

Thanks to about 20 years of experience on the surface metrology market, we have for core values a great knowledge of our customer's key material and product issues and the ability to efficiently meet his needs.



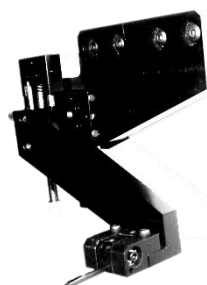
Wafer stress bow & warp calculation



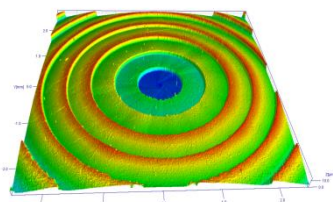
TSV



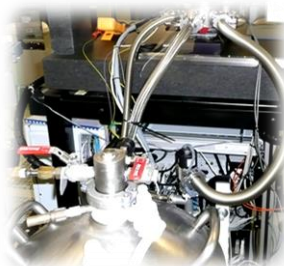
Cryogenic feeding with liquid N2



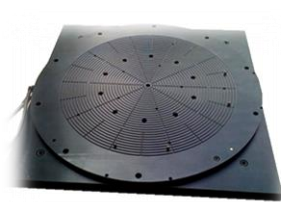
Micro-Force carbon Si Tun cantilever for contact fiber profilometry



Diffraction & fresnel lenses



Cryogenic tank and vacuum pump



Semiconductor wafer vacuum chucks